



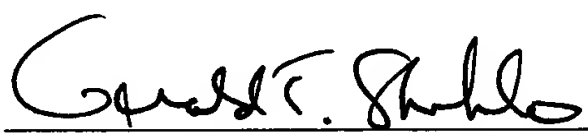
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1722

PATENT
Attorney Docket No. 1110/82821

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application)	Confirmation No.: 6761
)	
Applicant: Kozo Nakamura, et al.)	
)	<i>I hereby certify that this correspondence is</i>
Serial No.: 09/856,212)	<i>being deposited with the United Postal</i>
)	<i>Service as first class mail in an envelope</i>
Filed: May 18, 2001)	<i>addressed to: Mail Stop AMENDMENT,</i>
)	<i>Commissioner of Patents, P.O. Box 1450,</i>
For: PRODUCTION METHOD)	<i>Alexandria, VA, 22313-1450.</i>
FOR SILICON SINGLE)	
CRYSTAL AND)	<u>June 28, 2006</u>
PRODUCTION DEVICE FOR)	
SINGLE CRYSTAL INGOT,)	
AND HEAT TREATING)	
METHOD FOR SILICON)	
SINGLE CRYSTAL WAFER)	<i>Gerald T. Shekleton Reg. No. 27,466</i>
)	
Examiner: Matthew J. Song)	
)	
Art Unit: 1722)	

AMENDMENT

Mail Stop AMENDMENT
Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The Office Action of March 3, 2006 has been carefully reviewed and the following amendments and remarks are made in response thereto.